

Supplementary Figure:

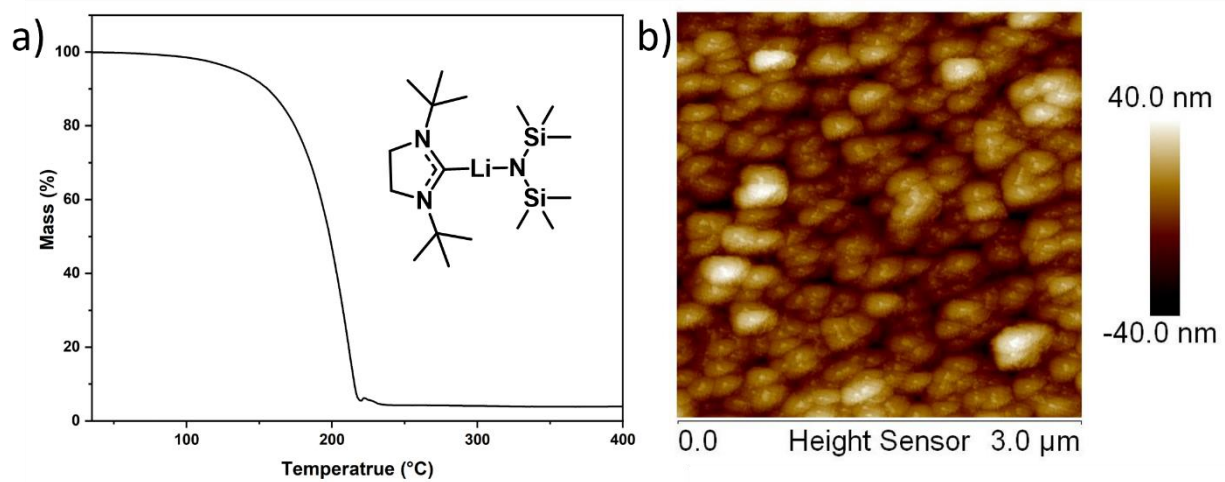


Fig. 1: a) Thermogravimetric analysis of the [Li(NHC)(HMDS)] precursor, b) AFM micrograph of a film deposited at 225 °C on Si substrate.